



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

#12/A

DB

6/24/03

Inventors: Blaine R. Spady; John D. Heaton
Assignee: Nanometrics Incorporated
Title: Metrology/Inspection Positioning System
Serial No.: 09/458,123 Filing Date: December 8, 1999
Examiner: Philip Sana Natividad Group Art Unit: 2877
Docket No.: NAN035 US Confirmation No.: 8470

Santa Clara, California
June 10, 2003

COMMISSIONER FOR PATENTS
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO OFFICE ACTION

Dear Sir:

This Response to Office Action is responsive to the March 19, 2003 Office Action, which has a statutorily shortened period for response that ends June 19, 2003. Please enter the following amendments before taking action on the merits of the above-referenced application.

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